Special Issue

Recent Development of Quantum Sensing and Metrology

Message from the Guest Editor

Quantum sensing and metrology aims to achieve precision beyond the standard quantum limit in parameter estimation. In recent years, the techniques that exhibit quantum enhancement in sensing and imaging have been intensively and extensively developed in diverse areas for various purposes. The present Special Issue is devoted to bringing together recent studies on quantum sensing and metrology from both theoretical and experimental perspectives. For this Special Issue, we invite researchers to submit comprehensive review papers and original research articles covering all aspects of quantum sensing, metrology, imaging, illumination, and parameter estimation. I look forward to receiving your excellent contribution to this Special Issue.

Guest Editor

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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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